

L Number	Hits	Search Text	DB	Time stamp
25	2	("1930905"   "2137852").PN.	USPAT	2004/11/03 08:27
26	14	4546658.URPN.	USPAT	2004/11/03 08:27
89	2	("5578766").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 08:52
90	2	("6450040").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 09:11
91	9	("3145563"   "3251222"   "3355935"   "3582690"   "3585415"   "3761784"   "4480488"   "5770803"   "5886543").PN.	USPAT	2004/11/03 08:52
92	4	3145563.URPN.	USPAT	2004/11/03 09:07
93	8	((("6091022") or ("5869766") or ("5760675") or ("5939817") or ("4701660") or ("3088323") or ("4556814") or ("4419598")).PN.	USPAT	2004/11/03 09:20
94	7	4419598.URPN.	USPAT	2004/11/03 09:15
95	6	("2311617"   "3283590"   "3417322"   "3492513"   "3739201"   "3805601").PN.	USPAT	2004/11/03 09:17
96	89951	310/\$7.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 09:20
97	431	310/\$7.ccls. and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 09:21
98	51	(310/\$7.ccls. and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 09:25
99	19	) and (semiconductor substrate).clm. ((310/\$7.ccls. and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 09:26
100	19	) and (semiconductor substrate).clm.) and electrode.clm. ("2408816"   "3714476"   "3801838"   "3948089"   "4480488"   "4512431"   "4604544"   "4816713"   "5371472"   "5537883"   "5682000"   "5739626"   "5747671"   "5777231"   "5777239"   "5852245"   "5886456"   "6271621"   "6396200").PN.	USPAT	2004/11/03 09:35
101	0	6617764.URPN.	USPAT	2004/11/03 09:39
142	2	("4546658").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 11:18
143	1	((("4546658").PN.) and (substrate semiconductor silicon)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 11:19
-	2518	(73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 09:40
-	311	((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 09:20

-	56	((((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 09:25
-	16	) and (semiconductor substrate).clm. (((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 09:26
-	13	) and (semiconductor substrate).clm.) and electrode.clm. ((((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 09:41
-	6	) and (semiconductor substrate).clm.) and electrode.clm.) and current ((((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 09:49
-	7	) and (semiconductor substrate).clm.) and electrode.clm.) and current.clm. ("3351786"   "4320664"   "4703658"   "4771639"   "4833929"   "4993266"   "5142914").PN.	USPAT	2004/11/02 09:45
-	3	5349873.URPN.	USPAT	2004/11/02 09:48
-	7	((((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 10:03
-	10	) and (semiconductor substrate).clm.) and electrode.clm.) and current) not ((((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.		
-	4	) and (semiconductor substrate).clm.) and electrode.clm.) and current.clm.) (("5341688") or ("4833929") or ("4680606") or ("4419598")).PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 10:04
-	175813	kabushiki.as.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 11:18
-	2438	kabushiki.as. and (force pressure transducer).ti.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 11:19
-	124	(kabushiki.as. and (force pressure transducer).ti.) and semiconductor.ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 11:20
-	150	(kabushiki.as. and (force pressure transducer).ti.) and electrode.ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 11:20

-	28	((kabushiki.as. and (force pressure transducer).ti.) and semiconductor.ab.) and electrode.ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT USPAT	2004/11/02 11:42
-	7	("3351786"   "4320664"   "4703658"   "4771639"   "4833929"   "4993266"   "5142914").PN.		2004/11/02 11:27
-	2	("3149488"   "4833929").PN.	USPAT	2004/11/02 11:28
-	19	4993266.URPN.	USPAT	2004/11/03 11:18
-	2	("4993266").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 12:05
-	105	((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and electrode near5 ((top face end oppos\$5) and (bottom face other end oppos\$5))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 12:06
-	40	((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 12:59
-	16	) and electrode near5 ((top face end oppos\$5) and (bottom face other end oppos\$5)) (((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 12:07
-	24	) and (semiconductor substrate).clm.) and electrode near5 ((top face end oppos\$5) and (bottom face other end oppos\$5)) (((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/02 13:01
-	6	) and electrode near5 ((top face end oppos\$5) and (bottom face other end oppos\$5))) NOT (((73/760,763,774,781,777,862.381,862.474,862.68,862.621).CCLS.) and (force near3 (sens\$4 evaluat\$5 estimat\$5 cell rate comput\$5 detect\$4 test\$4 meter gauge transducer measur\$4 indicat\$4 identif\$4 monitor\$4 determina\$4)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/11/03 08:50
-	14	) and (semiconductor substrate).clm.) and electrode near5 ((top face end oppos\$5) and (bottom face other end oppos\$5))) and (semiconductor) 4546658.URPN.	USPAT	2004/11/02 13:06
-	19	("3614485"   "3634787"   "4050530"   "4144747"   "4215570"   "4294105"   "4372173"   "4546658"   "4642508"   "4789804"   "5023503"   "5232063"   "5362929"   "5684276"   "5852229"   "5869763"   "5946795"   "5962786"   "6080939").PN.	USPAT	2004/11/02 13:09